						SHEET <u>12</u>	OF <u>26</u>		
INFORMATION DISCLOSURE CITATION IN AN APPLICATION C (PTO-1449)					ATTY. DOCKET NO. 7720/FPS/MMCS/APC	SERIAL NO. 10/632,107			
HAR B 3 2005 BY (PTO-1449)					APPLICANT Alexander T. SCHWARM et al.				
					FILING DATE	GROUP	GROUP		
					August 1, 2003	2812			
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EXAMINER'S INITIALS	PATENT APP. NO.	FILING DATE	NAME		TITLE		CLASS	SUB- CLASS	
	09/363,966	07/29/99	Arackaparambil et		omputer Integrated Manufact	uring			

APP. NO.	DATE	NAME	TITLE	CLASS	CLASS
09/363,966	07/29/99	Arackaparambil et al.	Computer Integrated Manufacturing Techniques		
09/469,227	12/22/99	Somekh et al.	Multi-Tool Control System, Method and Medium		
09/619,044	07/19/00	Yuan	System and Method of Exporting or Importing Object Data in a Manufacturing Execution System		
09/637,620	08/11/00	Chi et al.	Generic Interface Builder		
09/656,031	09/06/00	Chi et al.	Dispatching Component for Associating Manufacturing Facility Service Requestors with Service Providers		
09/655,542	09/06/00	Yuan	System, Method and Medium for Defining Palettes to Transform an Application Program Interface for a Service		
09/725,908	11/30/00	Chi et al.	Dynamic Subject Information Generation in Message Services of Distributed Object Systems		
09/800,980	03/08/01	Hawkins et al.	Dynamic and Extensible Task Guide		
09/811,667	03/20/01	Yuan et al.	Fault Tolerant and Automated Computer Software Workflow		
09/927,444	08/13/01	Ward et al.	in Semiconductor Manufacturing Processes		
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09/943,955	08/31/01	Shanmugasundram et al.	Polishing Device Providing Manipulation of Removal Rate Profiles		
09/998,372	11/30/01	Paik	Pad Conditioner Directional Velocity to Improve Pad Life		
09/998,384	11/30/01	Paik	Conditioning of Chemical Mechanical Polishing Pad		
	09/469,227 09/619,044 09/637,620 09/656,031 09/655,542 09/725,908 09/800,980 09/811,667 09/927,444 09/928,473 09/928,474 09/943,383 09/943,955 09/998,372	09/469,227 12/22/99 09/619,044 07/19/00 09/637,620 08/11/00 09/656,031 09/06/00 09/655,542 09/06/00 09/725,908 11/30/00 09/800,980 03/08/01 09/811,667 03/20/01 09/927,444 08/13/01 09/928,473 08/14/01 09/928,474 08/14/01 09/943,383 08/31/01 09/943,955 08/31/01 09/998,372 11/30/01	al. 09/469,227 12/22/99 Somekh et al. 09/619,044 07/19/00 Yuan 09/637,620 08/11/00 Chi et al. 09/656,031 09/06/00 Chi et al. 09/655,542 09/06/00 Yuan 09/725,908 11/30/00 Chi et al. 09/800,980 03/08/01 Hawkins et al. 09/811,667 03/20/01 Yuan et al. 09/927,444 08/13/01 Ward et al. 09/928,473 08/14/01 Krishnamurthy et al. 09/928,474 08/14/01 Shanmugasundram et al. 09/943,383 08/31/01 Shanmugasundram et al. 09/943,955 08/31/01 Shanmugasundram et al. 09/998,372 11/30/01 Paik	al. Techniques Multi-Tool Control System, Method and Medium 09/619,044 07/19/00 Yuan System and Method of Exporting or Importing Object Data in a Manufacturing Execution System 09/637,620 08/11/00 Chi et al. Generic Interface Builder 09/656,031 09/06/00 Chi et al. Dispatching Component for Associating Manufacturing Facility Service Requestors with Service Providers 09/655,542 09/06/00 Yuan System, Method and Medium for Defining Palettes to Transform an Application Program Interface for a Service 09/725,908 11/30/00 Chi et al. Dynamic Subject Information Generation in Message Services of Distributed Object Systems 09/800,980 03/08/01 Hawkins et al. Dynamic and Extensible Task Guide 09/811,667 03/20/01 Yuan et al. Fault Tolerant and Automated Computer Software Workflow 09/927,444 08/13/01 Ward et al. Dynamic Control of Wafer Processing Paths in Semiconductor Manufacturing Processes 09/928,473 08/14/01 Koh Tool Services Layer for Providing Tool Service Functions in Conjunction with Tool Functions 09/943,383 08/31/01 Shanmugasundram et al. Experiment Management System, Method and Medium 109/943,383 08/31/01 Shanmugasundram et al. Experiment Management System, Method and Medium 109/998,372 11/30/01 Paik Control of a Chemical Mechanical Polishing Device Providing Manipulation of Removal Rate Profiles 11/30/01 Paik Feedforward and Feedback Control for Conditioning of Chemical Mechanical Polishing Pad Conditioner Directional Velocity to Improve Pad Life 109/998,384 11/30/01 Paik Feedforward and Feedback Control for Conditioning Pad Control of Chemical Mechanical Polishing Pad Conditioning Of Chemical Mechanical Polishing Pad Conditioner Directional Velocity to	al. Techniques O9/469,227 12/22/99 Somekh et al. Multi-Tool Control System, Method and Medium

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INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449) APPLICANT Alexander T. SCHWARM et al. FILING DATE August 1, 2003 U.S. PATENT DOCUMENTS EXAMINERS PATENT FILING NITIALS APPLICA TITLE CLASS CLASS

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	10/084,092	02/28/02	Arackaparambil et al.	Computer Integrated Manufacturing Techniques			
	10/100,184	03/19/02	Al-Bayati et al.	Method, System and Medium for Controlling Semiconductor Wafer Processes Using Critical Dimension Measurements			
, , , , , , , , , , , , , , , , , , , ,	10/135,405	05/01/02	Reiss et al.	Integration of Fault Detection with Run-to- Run Control			
	10/135,451	05/01/02	Shanmugasundram et al.	Dynamic Metrology Schemes and Sampling Schemes for Advanced Process Control in Semiconductor Processing			
	10/172,977	06/18/02	Shanmugasundram et al.	Method, System and Medium for Process Control for the Matching of Tools, Chambers and/or Other Semiconductor- Related Entities			
	10/173,108	06/18/02	Shanmugasundram et al.	Integrating Tool, Module, and Fab Level Control			
	10/174,370	06/18/02	Shanmugasundram et al.	Feedback Control of Plasma-Enhanced Chemical Vapor Deposition Processes		-	
	10/174,377	06/18/02	Schwarm et al.	Feedback Control of Sub-Atmospheric Chemical Vapor Deposition Processes		-	
•	10/377,654	03/04/03	Kokotov et al.	Method, System and Medium for Controlling Manufacturing Process Using Adaptive Models Based on Empirical Data			
	10/393,531	03/21/03	Shanmugasundram et al.	Copper Wiring Module Control			
EXAMINER				DATE CONSIDERED			

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